

DSX1000

Get More Out of Your Digital Microscope



Intelligent Innovation

"Fast failure analysis with guaranteed accuracy and repeatability"



Macro to Micro Versatility

- Large selection of lenses to find the best magnification, resolution, and working distance for your sample
- ► Coded free-angle observation system



Multiple Observations with a Single Click

- Change lenses and observation method quickly by pushing a button
- ► All observation methods are available at all magnifications



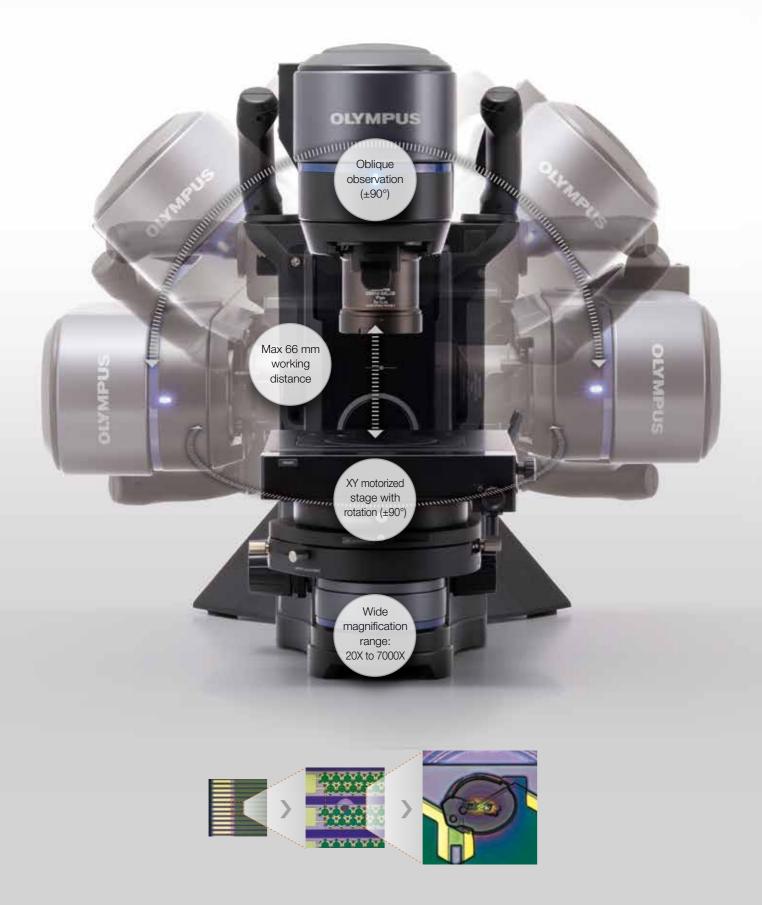
Be Confident in Your Results with Guaranteed Accuracy and Precision

- Accurate measurements with a telecentric optical system
- ► Both accuracy and repeatability are guaranteed at all magnifications



15 - 18

Macro to Micro Versatility



The microscope's 20X to 7000X magnification range enables you to conduct high-level, low-magnification overview observations and seamlessly zoom down to the micron level for detailed analysis.

The depth of field and a long working distance give you the flexibility to inspect larger samples, while the free-angle observation system enables you to image your sample from many directions.

The Tool to Solve Your Challenges

Rough Inspection and Micron-Level Analysis with One System

In the past, both high-magnification and low-magnification microscopes were needed to complete an inspection. Switching your samples between microscopes took time and required many setting adjustments.







- · Better objectives deliver better resolution
- · Long working distance
- · Deep depth of focus
- · Quick and easy lens replacement

DSX1000

Complete your inspection with one easy-to-use system.

High-Resolution Images at High Magnification

When inspecting uneven samples, it is important to maintain a safe distance between the lens and sample to keep from damaging it. To see details, you need to increase the magnification, but this typically results in worse resolution.







DSX1000

High-quality images at high magnification with advanced optics.

Minimize the Chance of Crashing into Your Sample

If the distance between your sample and the lens is too small, the objective can crash into the sample during analysis, potentially damaging it.





DSX1000

Observe uneven samples without bumping into them.

Choose the Best Lens for Your Analysis

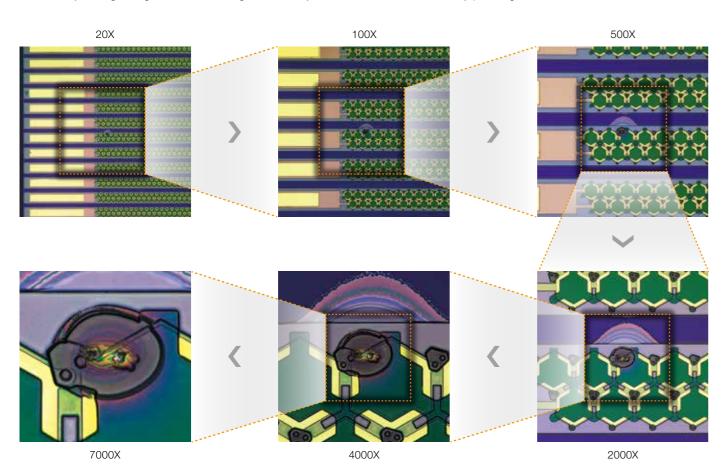
Our lineup of 17 objective lenses, including super long working distance and high numerical aperture options, provides the flexibility to obtain a wide range of images.



For more information on our lenses, see pages 27 and 28.

See the Whole Picture: 20X to 7000X Magnification Range

Seamlessly change magnification from high-level analysis to detailed observation by pushing a button.



Minimize the Chance of Crashing into Your Sample

The DSX1000 system offers a wide depth of field and a long working distance, so you can observe uneven samples with less chance of causing damage.



High Resolution and a Long Working Distance in One Objective

Objectives combining high resolution and long working distance enable you to analyze large, uneven samples, such as automobile and machines parts, that were difficult to inspect in the past using an optical microscope.



XLOB series

Exceptional Resolution with a 0.95 Numerical Aperture

The DSX1000 digital microscope enjoys the full benefits of optical microscope lenses. Their chromatic aberration correction enables you to see the fine details in your sample.

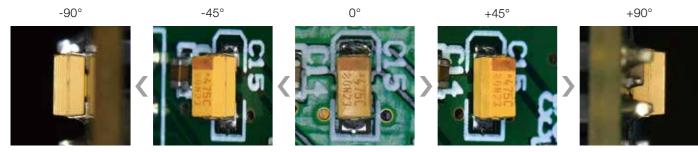


See Your Sample from Many Angles

Oblique observation (±90°)

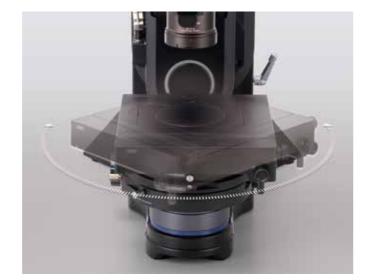
The eucentric optical design maintains a good visual field when tilted or when the stage is rotated, enabling you to observe your sample from many angles. This flexibility frees you from only having the option to observe your samples directly from above, helping you spot hard-to-see defects.

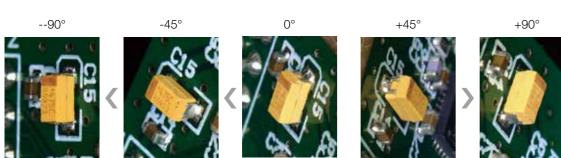




Rotational observation (±90°)

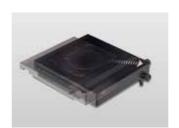
The stage rotates 90 degrees for even more flexibility in how you view your sample.





Always Know Your Angles

The system automatically tracks the inclination and angle rotation information for each image.



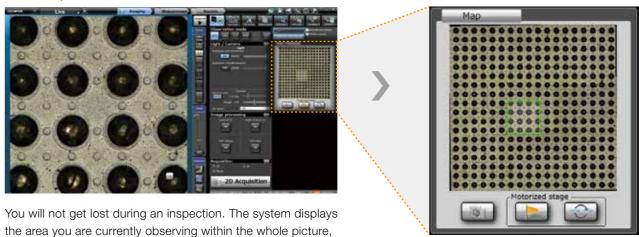


Movement of rotating stage

Inclination angle sensor



Micro map function



Easy-to-Use Console

even in zoom mode.



Multiple Observations with a Single Click



Six Observation Methods



Console



The DSX1000 microscope offers flexibility to make your inspection workflow faster and easier. Changing observation is as simple as turning a dial while switching between Six different observation methods requires only the push of a button.

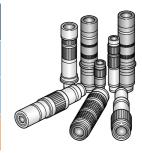
Instant Switching Saves Time

Conventional systems may only offer one or two observation methods, limiting what you can see in your sample.

The DSX1000 microscope offers various observation methods from which you can choose the one that works best for your job.

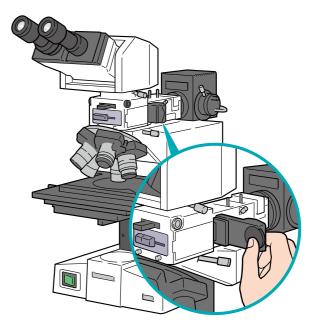
Supported Observation Methods for Conventional Digital Microscopes

| | Observation method A | Observation method B | Observation method C |
|----------------------|-------------------------|-------------------------|----------------------|
| Lens magnification A | | | Supported |
| Lens magnification B | | | Supported |
| Lens magnification C | Supported | Conditionally supported | |





Generally, replacing lenses on an optical microscope is cumbersome and some illumination methods may not be supported.



DSX1000

Choose from 6 observation methods, and switch between them with a single click.

9

Instantly switch

between them

Change Magnification Quickly and Easily

With some digital microscopes, you need to replace the object lens to adjust the magnification. This can be a slow process, potentially requiring you to remove the camera cable each time and also must be restart the software. During this process, you might lose your view on the object forcing you to spend time navigating back to the correct spot.

The DSX1000 enables you to easily and quickly change magnification from the macro to the micro range, minimizing the chance of losing the target object.

Quick Magnification Change with a Sliding Nosepiece

You can attach two objective lenses to the head at the same time and quickly change the magnification just by sliding the lens

Instantly Switch the Lens Attachment

Objective lenses can be quickly switched you to find the best magnification for your inspection. When the lens is replaced, magnification and visual field information will automatically be updated.



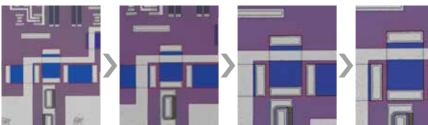


Fast Motorized Optical Zoom

Optically zoom in and out by turning the console dial. The optical zoom head covers wide range of magnifications with a single objective. It's fully motorized, helping you to eliminate common errors that may occur when manually setting the zoom.







A single lens supports up to 10X zoom ratio.

Change Observation and Illumination Methods by Pushing a Button

With some microscopes, illumination methods are depend on your choice of lens, and changing illumination can be time consuming. The DSX1000 system makes this process fast, simple, and easy—just push a button.



Simple Light Adjustment with Knob Dial

*Lighting is adjusted differently depending on the observation method.















Easy-to-Use Console

The multifunction console helps you do your work quickly. For example, you can easily capture 2D or 3D images or move the XYZ stage with one click.



Integrated Observation Methods

Easily switch between brightfield (BF), oblique, darkfield (DF), MIX (BF and DF), simple polarization (PO), differential interference contrast (DIC), and contrast enhancement observation functions. This flexibility enables you to handle almost any microscope inspection task.

MIX (BF+DF)

Light comes from a ring around the lens

Easily detect scratches and defects that can be hard to find with a conventional microscope by combining the detection capabilities of darkfield (DF) to the visibility of brightfield (BF).







BF (Brightfield)

Good for flat samples

On a mirrored surface, scratches look dark against the surface, helping them stand out.



PO (Polarization)

Designed for polarizing samples

By orthogonally laying out two polarization filters, this method enables you to see the contrast and color according to your sample's polarization property.



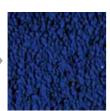


OBQ (Oblique)

Enhance your surface's unevenness

Use this method to enhance a surface's unevenness by shining the light from only one direction. This method is ideal for uneven or corrugated samples and cutting traces.





DIC (Differential Interference Contrast)

Visualize unevenness, foreign particles, scratches, and other defects at the nano level

This method enables you to visualize surface unevenness at the nano level. It's ideal for inspecting wafers, film, LCD ACF, and glass

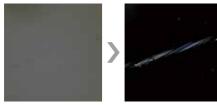




DF (Darkfield)

Best for detecting scratches and similar defects

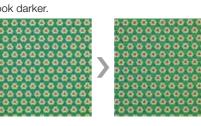
Scattering or reflected light is obliquely irradiated on the sample's surface, highlighting dust, scratches, and other objects. Dust and scratches appear bright in the visual field.



Contrast UP

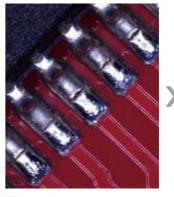
Emphasize your sample's contours

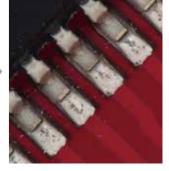
This method enhances the contrast by narrowing the optical element's aperture stop, enabling you to see sharp, vivid images. The bright parts look brighter, while the dark parts look darker.



Minimize Glare

The adaptor diffuses lighting to help eliminate glare and darkened slopes on a samples like a cylindrical metal surface.





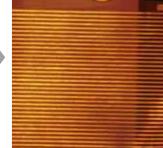
Without adaptor

Within adaptor

Eliminate Reflections

When observing a film's surface or an object through a transparent medium, such as glass, part of the surface can look very bright. An optical polarization plate is used with the adaptor to eliminate glare.





Without adaptor

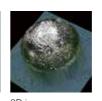
Within adaptor

High-Resolution Images at High Speed

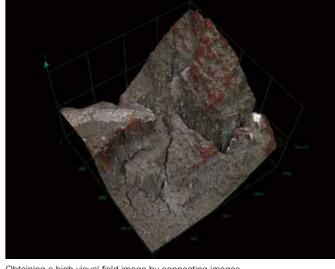
The microscope's advanced algorithms enable you to quickly capture 3D images by pushing a button.







Fully focused image 3D image



Obtaining a high visual field image by connecting images

Panoramic Images with Automatic Stitching

Capture 3D images over a wide area in panorama view. Stitch together a series of in-focus images to see your sample beyond the microscope's field of view.



Panoramic image

Be Confident in Your Results with Guaranteed* Accuracy and Precision



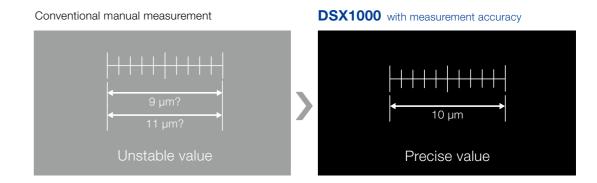
The microscope's telecentric optical system enables you to obtain very precise measurements while the guaranteed accuracy and precision bring confident in your results.

*To guarantee XY accuracy, calibration work must be undertaken by an Olympus service technician

Guaranteed Measurement Precision

Be Confident in Your Measurements

The precision of many general digital microscopes and optical microscopes is not guaranteed.



DSX1000

You can be confident in your measurement results with the guaranteed measurement precision.

On-Site Calibration

Even if the measurement precision of your microscope was guaranteed at the time of factory shipment, those results can be changed once installed.



DSX1000

Reliable measurement with on-site calibration.

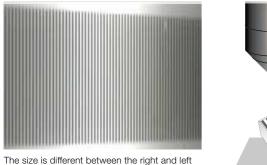
High-Precision Measurement

When imaging tall samples with conventional microscope, you may suffer from a convergence effect where the size of the object can look different depending on the point of focus. This effect makes it difficult to take accurate measurements. The DSX1000 system's telecentric optics eliminate this effect to achieve better measurement accuracy. When you need high-precision measurement, the DSX1000 is your choice.



(telecentric optical system)

DSX1000





The size is the same between the right and left edges in one visual field.

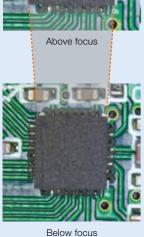
What is a telecentric optical system?

edges in one visual field.

Telecentric lenses have the same brightness at the center and edge of the visual field. Even if the sample moves vertically by adjusting the focus, the image size (magnification) does not change with telecentric lenses. This optical system enables you to capture an image of an entire sample faced up, which increases measurement precision.

When measuring the distance between two points in the images above and below focus, results can differ.





Telecentric optical system

The measurement result is the same between the images above and below focus

Telecentric lens

With a telecentric lens

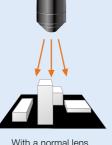
the target surface is not

hidden by unevenness.

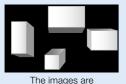
The image size

is the same.

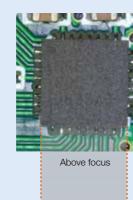




the target surface can be partially hidden by unevenness.



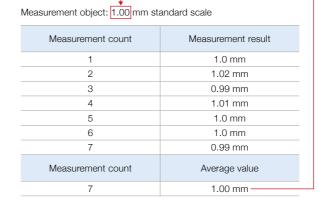
different in size.

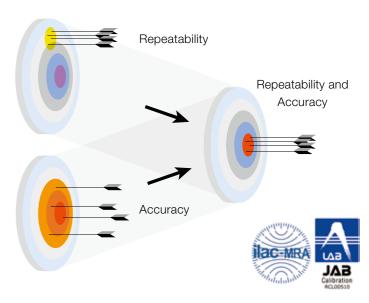


Below focus

Guaranteed Accuracy and Repeatability

Measurement accuracy and repeatability are guaranteed at all magnifications, so you can be confident with your measurement results.

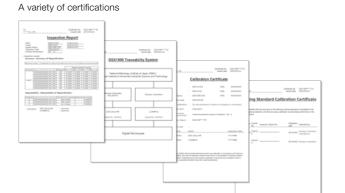




- •To issue certificates, calibration work must be undertaken by Olympus's dedicated service staff.
- •Olympus issues the calibration certificate authenticated by the ILAC-MRA calibration accreditation agencies.

Guaranteed Measurement Performance at Your Working Environment

When you purchase DSX1000 system, calibration will be done by a technician at your site to guarantee the same level of precision as it was shipped from the factory.



Keep Your Measurements Precise

To further reduce fluctuation in measurement precision, the objective lenses and zoom ratios needs to be calibrated. Normally, this is a timeconsuming process, but calibration setting can be done quickly and easily by the auto calibration feature.



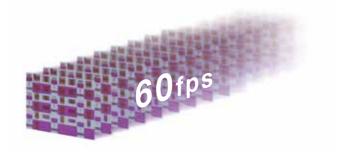


Calibration sample

Powerful Functionality Delivers Exceptional Value

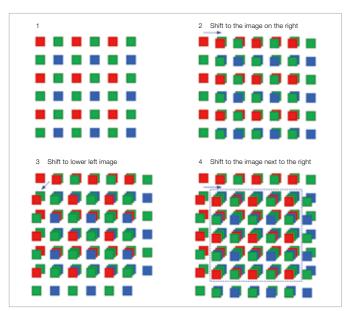
Smooth Live Imaging with a Fast 60 fps Frame Rate

With the same technology used in high-end, digital singlelens reflex cameras, the DSX1000 offers smooth imaging at 60 frames-per-second (fps) frame rate. Your images remain sharp even if you move the sample.



High-Resolution Imaging for High Color Reproduction

You can obtain high-resolution images with exceptional color reproduction and a small file size with the camera's built-in 3CMOS mode.

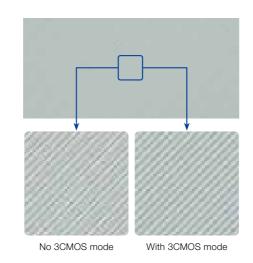


The DSX1000 system can achieve the same image quality as a three-plate camera by capturing images successively after shifting the sensor's position.

Sharp Low-Magnification Images without Flare

The microscope's advanced optical technology eliminates lens flares that are common at low magnification, resulting in sharp images.





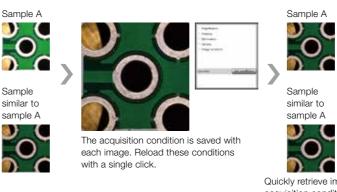
Preview Images from 6 Observation Methods

Instantly display sample images captured with 6 different observation methods by a single click. Choose the image that works best for your sample, and the setting will automatically be configured to make the best out of that observation method.



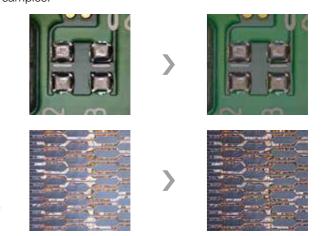
Retrieve Optimal Observation Condition

When you take an image, it contains information about the conditions when captured. You can recall these conditions by clicking on the image, making it easy to observe with the same conditions and settings.



Minimize Halation

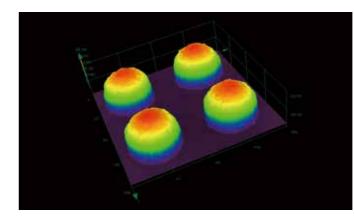
The HDR function combines multiple images captured at different exposures to show the fine structures in bright and dark areas while removing halation and glare from reflective samples.

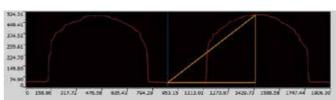


Quickly retrieve image acquisition conditions for efficient analysis.

Wide Variety of Measurements

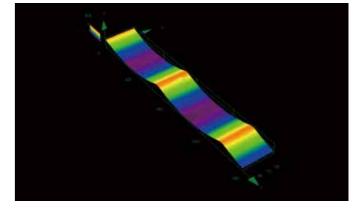
The system not only supports measurement of 2D properties like line width, surface area, angle, and diameter, but can also measure height, volume, cross-sectional area, and other properties required for 3D measurement.





Surface Roughness Measurement

You can easily see the picture of surface condition by performing line and surface roughness measurement quantitatively, using Ra and Rz parameters.



| Sq | 21.104 | Sak | 0.531 |
|------|-------------|------|-------------|
| Da | 1.996 | -Sp | 46.136 () |
| N . | 28.662 lans | - Sa | 74.798 (41) |
| la . | 18.311 | | |

Powerful Image Analysis Software

OLYMPUS Stream image analysis software facilitates specialized analysis, such as granularity measurement. OLS5000-BWS software is also available to make your inspection, from data acquisition to reporting, more efficient.

Flexible, One-Click Reporting

Instantly report your results in the format you like. This tool supports Excel, PDF, and RTF formats in addition to DSX-specific formats. You can also customize your report according to your desired format.

Automotive

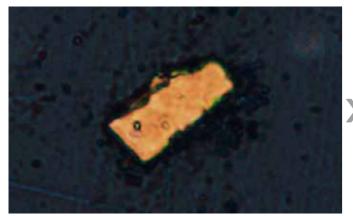
Observe foreign substances on the surface of painted car bodies to identify the source of the contamination

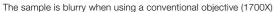


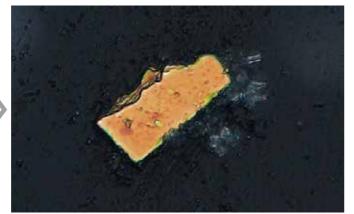
A painted car body

Solution

See clear object details at the same magnification.







Detect foreign substances by clearly visualizing even the air bubbles around them (DSX1000, 1700X)

Observe the cross-section of radiator fins to find welding defects



Radiator fin cross-section

Solution

With some systems, it can be time-confusing to choose the best observation method for your sample. With the DSX1000 system, select your observation method simply by pushing a button.



The sample is blurry when using a conventional objective (1700X)



DSX1000 Polized observation (300X), clearly visualize the peeling of the weld

Metal

Observe a fractured metal surface to analyze the damage cause



A fractured metal surface

Solution

Observation of a wide area can be done under high magnification with image stitching, but with some conventional system, the boundaries of stitched images remain visible.

The improved stitching algorithm of DSX1000 provides clear images without visible boundaries.



A 2 × 2 stitched image (1000X)

Observe Large Objects without Glare

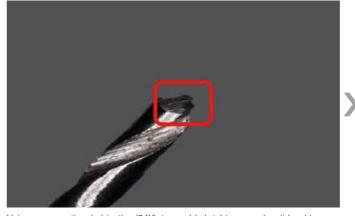


Drill tip

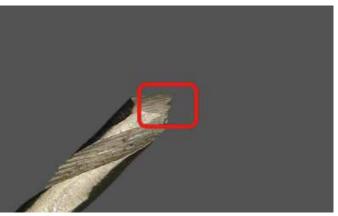


Brightness can easily be inequable when observing large three-dimensional objects, which makes it difficult to see the entire view of a sample.

Obtain a clear, glare-free overview of a large object with the DSX1000 microscope.



Using a conventional objective (24X), inequable brightness makes it hard to see the damaged area



Easy observation (24X) of damaged area with DSX1000 thanks to the flat lighting

Electronics

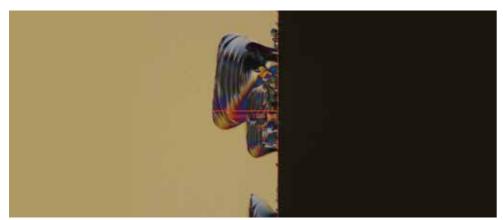
Measurement of integrated circuit (IC) chipping to determine the cause of failure



IC wafer before dicing

Solution

Not every digital microscope guarantees the accuracy and repeatability of measurements at all magnifications. You can rely on the DSX1000 measurement results with guaranteed measurement accuracy and repeatability.



Differential interference contrast (DIC) image (2500X), the edge of chipping is clearly visible

Multilayer capacitor surface inspection of defects and external dimension measurement

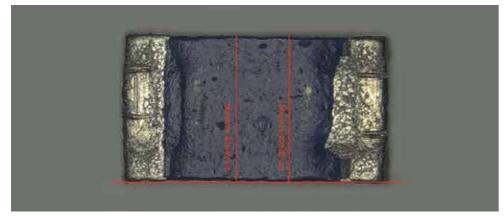


IC substrate

Solution

Reflection between the capacitor and dielectric makes it challenging for a conventional digital microscope to observe the entire surface.

Selecting the appropriate observation method can instantly be done with DSX1000 to find the best image.



Brightfield observation (1500X), surface observation and external dimension measurement can be done at the same time

Other analysis applications

Analyze the characteristics and defects in the cross-section of metallic materials

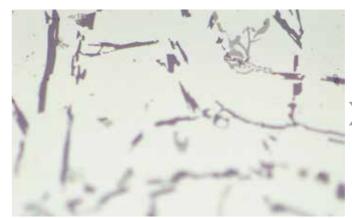


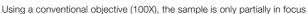
A polished samp

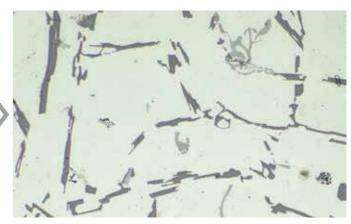
Solution

The DSX1000 system with OLYMPUS Stream software is capable of acquiring a fully-focused image of the entire sample regardless of unevenness or tilt on the polished surface.

This eliminates the need for re-polishing, leading to a reduction of effort and time.







DSX1000 objective (100X), the entire sample is fully focused regardless of irregularities

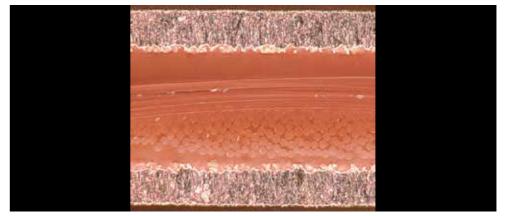
Analyze the glass fibers and resin in the cross-section of a printed wiring board's glass epoxy substrate



Printed wiring board

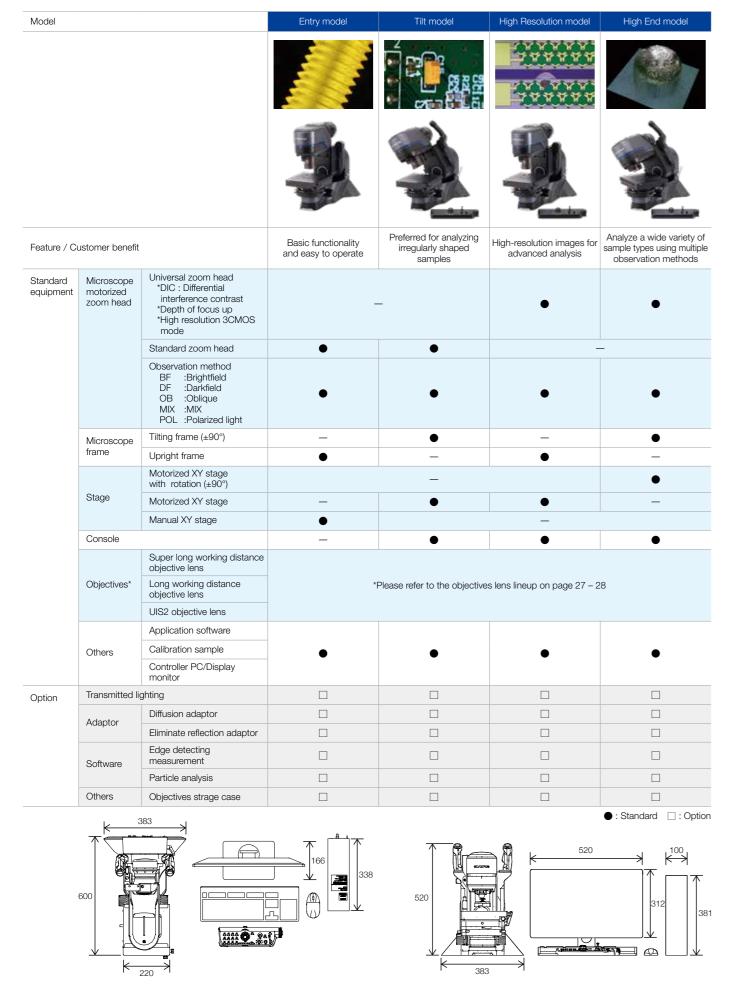
Solution

The glass epoxy's substrate is uneven due to etching, making it difficult for the microscope to clearly focus. The DSX1000 objectives' depth of focus and resolution achieve clear images across the entire cross-section.

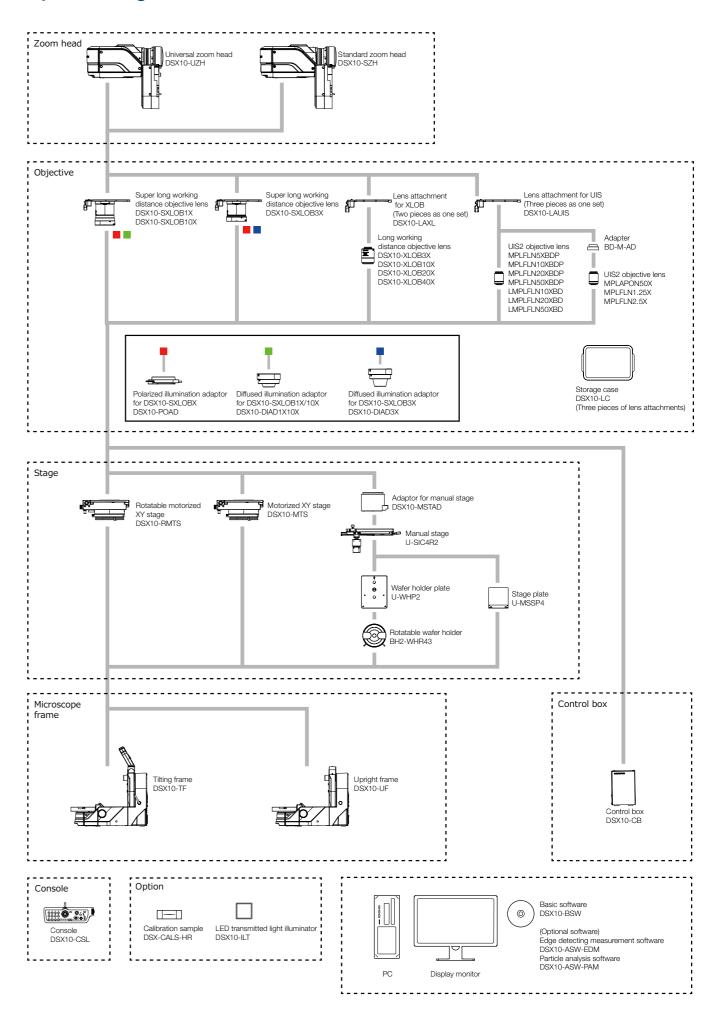


Darkfield (700X), individual glass fibers can be clearly observed

Lineup



System diagram



Objective Lenses

Super long working distance objective lens

 Provides a long working distance between the lens and sample



High-resolution, long working distance objective lens

 Delivers both high resolution and a long working distance



High-perfomance, high NA objective lens

• Delivers high performance at nano scale



| Magnification on monitor 20X | 40X | 100X 200X | 500X | 1000X | 2000X | 5000X | 7000X | | |
|------------------------------|------------|-------------|-------------|-------------|-------------|-------|-----------------------------|------------|-----------------------|
| Objective lens model | | | | | | | Working Distance (mm) | NA | Field of View (µm) |
| DSX10-SXLOB1X | 20 – 140X | | | | | | 51.7 | 0.03 | 19,200 – 2,740 |
| DSX10-SXLOB3X | | 42 – 420X | | | | | 66.1 | 0.09 | 9,100 – 910 |
| DSX10-SXLOB10X | | | 140 – 1400X | | | | 41.1 | 0.20 | 2,740 – 270 |
| DSX10-XLOB3X | | 42 – 420X | | | | | 30.0 | 0.09 | 9,100 – 910 |
| DSX10-XLOB10X | | | 140 – 1400X | | | | 30.0 | 0.30 | 2,740 – 270 |
| DSX10-XLOB20X | | | | 280 – 2800X | | | 20.0 | 0.40 | 1,370 – 140 |
| DSX10-XLOB40X | | | | | 560 – 5600X | | 4.5 | 0.80 | 690 – 70 |
| MPLFLN1.25X | 22.5 – 175 | x | | | | | 3.5 | 0.04 | 17,100 – 2,190 |
| MPLFLN2.5X | | 37.5 – 350X | | | | | 10.7 | 0.08 | 10,200 – 1,100 |
| MPLFLN5XBDP | | 70 – 700X | | | | | 12.0 | 0.15 | 5,480 – 550 |
| MPLFLN10XBDP | | | 140 – 1400X | | | | 6.5 | 0.25 | 2,740 – 270 |
| MPLFLN20XBDP | | | | 280 – 2800X | | | 3.0 | 0.40 | 1,370 – 140 |
| MPLFLN50XBDP | | | | | 700 – 7000X | | 1.0 | 0.75 | 550 – 55 |
| MPLAPON50X | | | | | 700 – 7000X | | 0.35 | 0.95 | 550 – 55 |
| LMPLFLN10XBD | | | 140 – 1400X | | | | 10.0 | 0.25 | 2,740 – 270 |
| LMPLFLN20XBD | | | | 280 – 2800X | | | 12.0 | 0.40 | 1,370 – 140 |
| LMPLFLN50XBD | | | | | 700 – 7000X | | 10.6 | 0.50 | 550 – 55 |
| | | | | | | +T | 4 0 40% 1 00%40 %10 | 201/ -11 - | . 50 1 |



Olympus lens processing system

We created an automatic lens processing system to deliver the highest possible quality optics. As a result, we are now able to process high precision lenses as fine as 1/10,000 mm.



Olympus advanced engineer development program leads to Yellow Ribbon Medal

In 2018, Olympus was awarded a Yellow Ribbon Medal for developing an advanced method to process high-precision objective lenses up to 2 µm. As part of the program, senior engineers mentored younger engineer in the art and science of lens manufacturing.



^{*}The DSX10-SXLOB1, 3, 10X, and DSX10-XLOB3X do not support PO observation.

 $^{{}^{\}star}\text{The MPLAPON50X}$ does not support DF and mixed observations.

^{*}The MPLFLN1.25, 2.5X support BF and OBQ observations.

^{*}Field of view: At aspect ratio 1:1 diagonal (with factory default value)

Specifications Main Unit Specifications

| | | | DSX10-SZH | | DSX10-UZH | | | | |
|--------------|---|-------------------------------|--|--|-------------------------------------|--|--|--|--|
| | Optical system | | Telecentric optical system | | | | | | |
| | Zoom ratio | | 10X (motorized) | | | | | | |
| | Zoom magnification meth | nod | | Motorized | | | | | |
| | Calibration | | | Automatic | | | | | |
| Optical | Lens attachment | | Quio up | k-switch, coded lens attachments aut date magnification and visual field info | omatically rmation | | | | |
| system | Maximum total magnifica | tion (on monitor) | 7,000X | | | | | | |
| | Working distance (W.D.) | | 66.1 - 0.35 mm | | | | | | |
| | Accuracy and | Accuracy*1 | ± 3% | | | | | | |
| | repeatability (X-Y plane) | Repeatability $3\sigma_{n-1}$ | 2% | | | | | | |
| | Repeatability (Z axis)*2 | Repeatability σ_{n-1} | | 1 µm | | | | | |
| | Image sensor | | | 1 / 1.2 inch, 2.35 million pixel color CN | MOS | | | | |
| | Cooling | | Peltier cooling | | | | | | |
| Camera | Frame rate | | | 60 fps (maximum) | | | | | |
| | Normal | | 1,200 × 1,200 (1:1) / 1,600 × 1,200 (4:3) | | | | | | |
| | Fine | | Not available | 1,200 × | 1,200 (1: 1) / 1,600 × 1,200 (4: 3) | | | | |
| | Super fine | | Not available | 3,600 × | 3,600 (1: 1) / 4,800 × 3,600 (4: 3) | | | | |
| | Color light source | | LED | | | | | | |
| Illumination | Lifetime | | 60,000 h (design value) | | | | | | |
| | BF (brightfield) | | Standard | | | | | | |
| | OBQ (oblique) | | Standard | | | | | | |
| | DF (darkfield) | | Standard LED ring divided into four divisions | | | | | | |
| Observation | MIX (brightfield+darkfield) |) | Standard Simultaneous observation of BF + DF | | | | | | |
| | PO (polarization) | | Standard | | | | | | |
| | DIC (differential interferen | ce) | Not available | | Standard | | | | |
| | Contrast up | | | Standard | | | | | |
| | Depth of focus up function | on | Not available | | Standard | | | | |
| | Transmitted lighting | | Standard*3 | | | | | | |
| Focus | Focusing | | | Motorized | <u> </u> | | | | |
| rocus | Stroke | | | 101 mm (motorized) | | | | | |
| When used | by Olympus or dealer ser I 20X or higher objective al DSX10-ILT is required | | ssary. To guarantee the accuracy of | XY, calibration with DSX-CALS-HR (ca | alibration sample) is required. | | | | |
| | Objective | | DSX10-SXLOB | DSX10-XLOB | UIS2 | | | | |
| Objective | | | D9Y IO-9YFOR | D9Y I 0-YFOR | UISZ | | | | |

| | · · | | | | | | |
|--------------------|--|----------------------|--|--|------------------|-------------------|--|
| | Objective | | DSX10-SXLOB | | DSX10-XLOB | UIS2 | |
| | Maximum sample height | | 50 mm | | 115 mm | 145 mm | |
| | Maximum sample height (free angle observation) | | | | 50 mm | | |
| Objective lens | Parfocal distance | | 140 mm | | 75 mm | 45 mm | |
| | Lens attachment | Integrated with lens | rated with lens Available | | | | |
| | Total magnification | | 20X - 1,400X | | 42X - 5,600X | 23X*4 - 7,000X | |
| | Actual F.O.V. | 19,200 µm - 270 µm | | | 9,100 μm - 70 μm | 17,100 μm - 50 μm | |
| Adoptor | Diffusion adaptor (option) | | Available | | Not available | | |
| Adaptor | Eliminate reflection adaptor (option | n) | Available | | Not available | | |
| Lens attachment | Number of objectives that can be attached | | Up to 1 piece (attachment is integrated with lens) | | Up to 2 pieces | | |
| Objective lens | case | | Three lens attachments can be stored | | | | |
| *4 Total magnif | cation when using MPLFLN1.25X | | | | | | |
| | Stage | | DSX10-RMTS | | DSX10-MTS | U-SIC4R2 | |
| | XY stage: motorized / manual | М | flotorized (with rotation function) | | Motorized | Manual | |
| | | | | | | | |

| *4 Total magnification when using MPLFLN1.25X | | | | | | | | |
|---|---|---------------|---|--------|-------------------|---------------|------------------------------|--|
| Stage | | DSX10-RMTS | | | DSX10-MTS | U-SIC4R2 | | |
| | XY stage: motorized / manual | | Motorized (with rotation function) | | | Motorized | Manual | |
| | XY stroke | | Stroke priority mode : 100 mm × 100 mm Rotation priority mode : 50 mm× 50 mm | | | 100 × 100 mm | 100 × 105 mm | |
| Stage | Stage Rotation angle Display rotation angle Load-resistance | | Stroke priority mode : ±20° Rotation priority mode : ±90° | | | Not available | | |
| | | | GUI | | | Not available | | |
| | | | 5 kg (11 lb) | | lb) 1 kg (2.2 lb) | | | |
| Frame | Frame DSX-UF | | | DSX-TF | | Display | 23 - inch flat panel display | |
| Z-axis str | Z-axis stroke | | 50 mm (manual) | | | Resolution | 1,920 (H) × 1,080 (V) | |
| Tilt observ | ration | Not available | ±90° | | | | | |
| Tilt angle display Not available | | Not available | GUI | | | | | |

| Tilt angle method | Not available | Manual, fix / release handle | | |
|----------------------|--|------------------------------------|----------------------|----------------------------|
| | System Total | Upright frame syste | m | Tilt frame system |
| Weight (frame, head, | motorized stage, display, and console) | 43.7 kg (96.3 lb) 46.7 kg (103 lb) | | 46.7 kg (103 lb) |
| Power consumption | | 100 | - 120V / 220 - 240 \ | /, 1.1 / 0 .54A, 50 / 60Hz |

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 The information including guaranteed accuracy in this brochure is based on the condition set by Olympus. For details, refer to the Instruction Manual.
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